



## UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE  
 United States Patent and Trademark Office  
 Address: COMMISSIONER FOR PATENTS  
 P.O. Box 1450  
 Alexandria, Virginia 22313-1450  
 www.uspto.gov

## \*BIBDATASHEET\*

Bib Data Sheet

CONFIRMATION NO. 7420

SERIAL NUMBER 10/706,944	FILING DATE 11/14/2003 RULE	CLASS 216	GROUP ART UNIT 1746	ATTORNEY DOCKET NO. 101136-00103
-----------------------------	-----------------------------------	--------------	------------------------	--

## APPLICANTS

Takaei Sasaki, Saitama-ken, JAPAN;

Noriyuki Harashima, Saitama-ken, JAPAN;  
Satoshi Aoyama, Hyogo-ken, JAPAN; Shouichi Sakamoto, Hyogo-ken, JAPAN;*MK (verified)*

## \*\* CONTINUING DATA \*\*\*\*\*

This application is a DIV of 09/361,158 07/27/1999 PAT 6,685,848

*MK (verified)*

## \*\* FOREIGN APPLICATIONS \*\*\*\*\*

JAPAN 309010/1998 10/29/1998

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

\*\* 02/10/2004

Foreign Priority claimed	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY	SHEETS	TOTAL	INDEPENDENT
35 USC 119 (a-d) conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance	JAPAN	DRAWING 7	CLAIMS 2	CLAIMS 2
Verified and Acknowledged  Examiner's Signature	<i>mk</i>	<i>mk</i> Initials			

## ADDRESS

AREN'T FOX KINTNER PLOTKIN & KAHN, PLLC  
 SUITE 400  
 1050 CONNECTICUT AVENUE, N.W.  
 WASHINGTON, DC  
 20036-5339

## TITLE

Method and apparatus for dry-etching half-tone phase-shift films, half-tone phase-shift photomasks and method for the preparation thereof, and semiconductor circuits and method for the fabrication thereof

<input type="checkbox"/> All Fees
<input type="checkbox"/> 1.16 Fees ( Filing )
<input type="checkbox"/> 1.17 Fees ( Processing Ext. of
FILING FEE FEES: Authority has been given in Paper